Prof. Haedo Jeong

(Pusan National University, Korea)

Professor Haedo Jeong received B.S. degree from Pusan National University, Korea in 1987 and the M.S. degree and Ph.D. in mechanical engineering from KAIST, Korea in 1989 and from University of Tokyo, Japan in 1994, respectively. From 1989 to 1991, he worked at government research institutes of KIST and KITECH, where he was responsible for abrasive machining process such as grinding and polishing. In 1994, he joined at Japanese government project with RIKEN and Fujikoshi machinery, Japan as a post-doc. researcher to develop a CMP equipment. From 1995, he is working as a professor in the school of mechanical engineering as well as a director of CMP Lab at Pusan National University. He has also served as a director of LINC (Leaders in INdustry-university Cooperation) project. His research interests include wafering processes, chemical mechanical polishing and its post cleaning. He has authored more than 600 technical publications/presentations in the area of abrasive processing, 3D printing and CMP.   He is the emeritus president of Korea CMPUGM and an executive committee member of International Conference on Planarization/CMP Technology (ICPT) which is the largest CMP conference in the world. He is also a founder and president of G&P Technology which is one of the strongest semi-production CMP tool suppliers and expands its area to packaging and display. He is also an emeritus president of Korean Society of Precision Engineering (KSPE). Thanks to his contribution, he got many awards and medals from 30 different organizations including government. He may be reached at 82-51-510-2463 or by email hdjeong@pusan.ac.kr.